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Applicant(s): Steven M. George et al.

Serial No.: 09/896,955

Group Art Unit: 1762

Filed: June 29, 2001

Examiner: Meeks

For: METHOD FOR FORMING SiO<sub>2</sub> BY CHEMICAL VAPOR DEPOSITION AT ROOM TEMPERATURE

I HEREBY CERTIFY THAT THIS CORRESPONDENCE IS BEING SENT	
BY FACSIMILE ON January 6, 2004	
DATE OF DEPOSIT	
Gary C. Cohn	
PRINT OR TYPE NAME OF PERSON SIGNING CERTIFICATE	
SIGNATURE OF PERSON SIGNING CERTIFICATE	



Hon. Commissioner of Patents & Trademarks  
Washington, D.C. 20231

Sir:

RESPONSE B

This paper is submitted in response to the office action in this case mailed August 6, 2003. A two-month extension of time is hereby requested. The required fee is being submitted with this paper.

The examiner is respectfully requested to enter the following amendments and to reconsider the application in view of the following remarks.

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